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APPLICANT: TOYOTA MOTOR CORP;

INVENTOR :

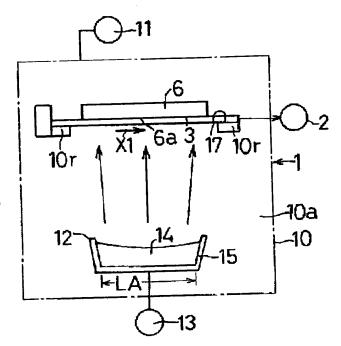
IZUMI ICHIRO;

INT.CL.

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TITLE

FORMATION OF THIN FILM



ABSTRACT: PROBLEM TO BE SOLVED: To provide a thin film forming method advantageous for forming a thin film in which the shapes of the openings of a mask are transferred with high precision.

> SOLUTION: A mask 3 having plural openings and a substrate 6 having the face 6a to be film-formed is used, and, in a stage in which the mask 3 is confronted with the face 6a to be film-formed, the face 6a to be film-formed is applied with film forming treatment of a thin film so as to transfer the shapes of the openings of the mask 3. The film forming treatment is executed in a state in which the mask 3 is applied with tension so as to suppress the warpage and deflection of the mask 3. The mask may have a double structure. Furthermore, the mask can be adhered to the face 6a to be film-formed in the substrate 6 by the magnetic attraction. It can be utilized for thin film formation in an organic EL element.

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